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16**Inventor Name Search Result**

Your Search was:

Last Name = MURUGESH

First Name = LAXMAN

Application#	Patent#	Status	Date Filed	Title	Inventor Name 19
<u>10854771</u>	Not Issued	030	05/25/2004	EROSION RESISTANT PROCESS CHAMBER COMPONENTS	MURUGESH, LAXMAN
<u>10797286</u>	Not Issued	030	03/09/2004	GAS DISTRIBUTOR HAVING DIRECTED GAS FLOW AND CLEANING METHOD	MURUGESH, LAXMAN
<u>10374533</u>	Not Issued	041	02/25/2003	METHOD AND APPARATUS FOR MODIFYING THE PROFILE OF NARROW, HIGH- ASPECT-RATIO GAPS USING RF POWER	MURUGESH, LAXMAN
<u>10336241</u>	Not Issued	041	01/03/2003	GAS NOZZLE FOR SUBSTRATE PROCESSING CHAMBER	MURUGESH, LAXMAN
<u>10057037</u>	Not Issued	071	01/24/2002	PROCESS ENDPOINT DETECTION IN PROCESSING CHAMBERS	MURUGESH, LAXMAN
<u>09819255</u>	<u>6375744</u>	150	03/27/2001	SEQUENTIAL IN- SITU HEATING AND DEPOSITION OF	MURUGESH, LAXMAN

				HALOGEN-DOPED SILICON OXIDE	
<u>09745918</u>	<u>6579811</u>	150	12/20/2000	METHOD AND APPARATUS FOR MODIFYING THE PROFILE OF NARROW, HIGH-ASPECT-RATIO GAPS THROUGH WAFER HEATING	MURUGESH, LAXMAN
<u>09633494</u>	<u>6450117</u>	150	08/07/2000	DIRECTING A FLOW OF GAS IN A SUBSTRATE PROCESSING CHAMBER	MURUGESH, LAXMAN
<u>09328709</u>	<u>6217658</u>	150	06/09/1999	SEQUENCING OF THE RECIPE STEPS FOR THE OPTIMAL LOW-DIELECTRIC CONSTANT HDP-CVD PROCESSING	MURUGESH, LAXMAN
<u>09264990</u>	<u>6200911</u>	150	04/21/1998	METHOD AND APPARATUS FOR MODIFYING THE PROFILE OF NARROW, HIGH-ASPECT-RATIO GAPS USING DIFFERENTIAL PLASMA POWER	MURUGESH, LAXMAN
<u>09169058</u>	<u>6159333</u>	150	10/08/1998	SUBSTRATE PROCESSING SYSTEM CONFIGURABLE FOR DEPOSITION OR CLEANING	MURUGESH, LAXMAN
<u>08868595</u>	<u>6136685</u>	150	06/03/1997	HIGH DEPOSITION RATE RECIPE FOR LOW DIELECTRIC CONSTANT FILMS	MURUGESH, LAXMAN
<u>08868286</u>	<u>5937323</u>	150	06/03/1997	SEQUENCING OF THE RECIPE STEPS FOR THE OPTIMAL LOW-K HDP-CVD PROCESSING	MURUGESH, LAXMAN

<u>08867683</u>	<u>5994662</u>	150	05/29/1997	UNIQUE BAFFLE TO DEFLECT REMOTE PLASMA CLEAN GASES	MURUGESH , LAXMAN
<u>08704428</u>	<u>5811356</u>	150	08/19/1996	REDUCTION IN MOBILE ION AND METAL CONTAMINATION BY VARYING SEASON TIME AND BIAS RF POWER DURING CHAMBER CLEANING	MURUGESH , LAXMAN
<u>08632741</u>	<u>5997685</u>	150	04/15/1996	CORROSION-RESISTANT APPARATUS	MURUGESH , LAXMAN
<u>08614594</u>	<u>5810937</u>	150	03/13/1996	USING CERAMIC WAFER TO PROTECT SUSCEPTOR DURING CLEANING OF A PROCESSING CHAMBER	MURUGESH , LAXMAN
<u>08499983</u>	<u>5811195</u>	150	07/10/1995	CORROSION-RESISTANT ALUMINUM ARTICLE FOR SEMICONDUCTOR PROCESSING EQUIPMENT	MURUGESH , LAXMAN
<u>08291367</u>	<u>5756222</u>	150	08/15/1994	CORROSION-RESISTANT ALUMINUM ARTICLE FOR SEMICONDUCTOR PROCESSING EQUIPMENT	MURUGESH , LAXMAN

Inventor Search Completed: No Records to Display.

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16**Inventor Name Search Result**

Your Search was:

Last Name = AHR

First Name = GARY

Application#	Patent#	Status	Date Filed	Title	Inventor Name 2
10057037	Not Issued	071	01/24/2002	PROCESS ENDPOINT DETECTION IN PROCESSING CHAMBERS	AHR, GARY R.
09338702	Not Issued	161	06/23/1999	SCENT DIFFUSING DEVICE	AHRENS , GARY P.

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